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10/22/02
DRAFT
Attorney Docket: 622/48561
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: MARTIN DUBS ET AL.

Serial No.: 09/484,421 Group Art Unit: 1753

Filed: JANUARY 18, 2000 Examiner: G. CANTELMO

Title: SPUTTER CHAMBER AS WELL AS VACUUM TRANSPORT CHAMBER AND VACUUM HANDLING APPARATUS WITH SUCH CHAMBERS

AFTER-FINAL REPLY UNDER 37 CFR §1.116
EXPEDITED HANDLING REQUESTED

Commissioner for Patents
Washington, D.C. 20231

Sir:

The following is responsive to the Office Action mailed on or about April 18, 2002.

IN THE CLAIMS:

A version with markings to show the changes made is attached to this Reply.

Please amend Claims 35, 47, 48, 50 and 58 as follows:

35. (Amended) Sputtering chamber comprising at least one sputtering source with a new sputter surface at least approximately symmetrical with respect to a first axis oriented perpendicular to said new sputter surface, a